Networking Reception on Wednesday, April 24, 7:30–9:00 pm. This new event is for attendees who want to showcase their research in an interactive and fun way. More information is available on the 2019 MRS Spring Meeting website.

The **MRS/Cambridge University Press Publications Booth 100** will be featured in the Exhibit Hall. Stop by to learn about the MRS Publications Portfolio and receive 20% off all book purchases.

The popular **Science as Art** competition is open to all registered Meeting attendees. Multiple first-place and second-place awards of $400 and $200, respectively, will be presented at the Meeting. Guidelines are listed on the 2019 MRS Spring Meeting website.

The deadline to preregister for the 2019 MRS Spring Meeting is April 5 (5:00 pm ET). International travelers are reminded to begin the visa process early. For additional information on the Spring Meeting, contact MRS Member Services, e-mail info@mrs.org and tel. 724-779-3003.

The MRS website can be accessed for updated information on confirmed talks and details on special events, information on obtaining a visa, and preregistration at.mrs.org/spring2019.

2019 MRS SPRING MEETING REGISTRATION RATES

	PREREGISTRATION before 5:00 pm (ET) April 5, 2019	ON-SITE REGISTRATION after 5:00 pm (ET) April 5, 2019
Meeting Registration	$715	$845
Meeting Registration with MRS Member Discount	$565	$705
Student Registration (Proof of student status required.)	$160	$200
Student Registration with MRS Member Discount	$130	$160
Retired	$190	$215
Unemployed	$160	$200

2019 MRS Spring Meeting registrations include MRS Membership from July 1, 2019 to June 30, 2020.

Van Swygenhoven-Moens to present Kavli lecture during 2019 MRS Spring Meeting plenary session

Helena Van Swygenhoven-Moens will present The Fred Kavli Distinguished Lectureship in Materials Science on Tuesday, April 23. She is a professor at the École Polytechnique Fédérale de Lausanne (EPFL) in the Materials Science Institute; she also leads the Neutrons and X-rays for Mechanics of Materials Laboratory and heads the Photons for Engineering and Manufacturing Research Group at the Paul Scherrer Institute in Switzerland.

Helena's presentation is titled, "Synchrotron Light to Investigate Materials *In Operando*." Synchrotron radiation beams are now sufficiently bright and detectors are sufficiently fast that scattering and x-ray absorption data can be followed in real time for a material under action. With the use of synchrotron radiation, high-resolution computer-aided tomographic microscopy is possible. One can now look at the formation of pores, microcracks, or gas bubbles during the interaction of a material with an external environment.

Helena studied physics at the Vrije Universiteit Brussels and received her PhD degree in physics from the Central Jury in Belgium. After a professional break for motherhood, she continued her career with a Marie-Heim Vögtlin Grant from the Swiss National Science Foundation. Helena is a Fellow of the Materials Research Society, elected member of the Royal Academy of Science of Belgium, and an advanced grant holder from the European Research Council. For many years, she chaired the International Board of the International Committee of Strength of Materials, was a member of the Scientific Advisory Committee of the European Spallation Source, was on the peer review panel of *Diamond*, and was on the beamline review panels of ESRF. Helena also serves on the engineering expert panel of the National Science Foundation Flanders and on expert panels of the ERC.

The core of her work is the development and use of *in situ* experiments at synchrotron and neutron facilities, with the aim to follow a material's microstructure *in operando* and to provide synergies between experiments and computational modeling. Helena's research focuses on the link between synthesis and microstructure, including laser-based additive manufacturing methods and the connection between microstructure and mechanical behavior of a variety of materials, ranging from nanostructured materials for watch components, superelastic alloys for medical applications, and advanced steels and lightweight alloys for structural applications. Through her ERC advanced grant (MULTIAX), Helena addresses non-proportional multiaxial straining covering the gap between our current knowledge of mechanical behavior derived from uniaxial deformation tests and the engineering reality of applications and processing routes.

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Phoenix Convention Center, North Building, 300 Level, Exhibition Halls C–E
Tuesday, April 23, 2:00 pm – 7:00 pm • Wednesday, April 24, 11:00 am – 7:00 pm

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